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9/287,602

7, 1999

SCRUBBER FOR TREATING
GAS GENERATED DURING
SEMICONDUCTOR
UFACTURING PROCESS

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JAN 08 2001
PATENT & TRADEMARK OFFICE


Group Art Unit: 1764
Examiner: Varcoe, F.

Atty. Dkt. No. 5480-00200

CERTIFICATE OF MAILING
37 C.F.R. § 1.8

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: **Box: Non-Fee Amendment,** Assistant Commissioner for Patents, Washington, D.C. 20231, on the date indicated below:

January 4, 2001



Kevin L. Daffer

**For: GAS SCRUBBER FOR TREATING
THE GAS GENERATED DURING
THE SEMICONDUCTOR
MANUFACTURING PROCESS**

AMENDMENT; RESPONSE TO OFFICE ACTION DATED OCTOBER 4, 2000

Box: Non-Fee Amendment
Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir/ Madam:

This paper is submitted in response to the Office Action dated October 4, 2000 to further highlight reasons why the application is in condition for allowance.

Please amend the case as follows:

In the Specification:

Please replace the specification of the originally claimed case, excluding the claims, with the substitute specification in Attachment A. A “marked-up” copy of the original specification is included in Attachment B, showing the changes made to produce the substitute specification. The